

Notice of References Cited	Application/Control No. 10/827,375	Applicant(s)/Patent Under Reexamination LIANG ET AL.	
	Examiner Paul D. Kim	Art Unit 3729	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,600,404	07-2003	Kajino, Takashi	336/200
*	B	US-6,429,764	08-2002	Karam et al.	336/200
	C	US-			
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	K	US-			
	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Novel Fabrication Of Electroplated 3D Micro-Coils Using 3D Photolithography Of Thick Photoresist"; Yoon, J.-B.; Han, C.-H.; Yoon, E.-S.; Kim, C.-K.; Microprocesses and Nanotechnology Conference, 1998 International; 13-16 July 1998; Pages:85 - 86.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.